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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of

AOKI et al

Atty. Ref.: 4074-7

Serial No. 10/689,666

Group:

Filed: October 22, 2003

Examiner:

For: PHOTOMASK DEFECT TESTING METHOD,
PHOTOMASK MANUFACTURING METHOD AND
SEMICONDUCTOR INTEGRATED CIRCUIT
MANUFACTURING METHOD

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Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

Sir:

STATUS INQUIRY

An application was filed on October 22, 2003. However, since then applicant has not received any Official Action from the Patent Office regarding the application. Inquiry is made as to when an Action will be forthcoming. **Please direct any response to this inquiry to Linda Hull at telephone number (703) 816-4127.**

Respectfully submitted,
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April 21, 2005

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